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U.S. UTILITY Patent Application

PATENT NUMBER and  
ISSUE DATE

APPL. NUM	FILING DATE	CLASS	SUBCLASS	GAU	EXAMINER
10064703	08/08/2002	427	248.11	1762	Meeks

\*\*APPLICANTS: Lin Frank;

\*\*CONTINUING DATA VERIFIED:

\*\* FOREIGN APPLICATIONS VERIFIED:

PG-PUB	DO NOT PUBLISH <input type="checkbox"/>	RESCIND <input type="checkbox"/>	ATTORNEY DOCKET NO
Foreign priority claimed <input type="checkbox"/> yes <input checked="" type="checkbox"/> no		9458-US-PA	
35 USC 119 conditions met <input type="checkbox"/> yes <input checked="" type="checkbox"/> no			
Verified and Acknowledged Examiners's Initials <i>[Signature]</i>			

TITLE : Method for depositing thin film using plasma chemical vapor deposition

U.S. DEPT. OF COMM. / PAT & TM-PTO-436L (Rev. 12-94)

NOTICE OF ALLOWANCE MAILED		Assistant Examiner	CLAIMS ALLOWED	
			Total Claims	Print Claim for O.G.
ISSUE FEE		Primary Examiner	DRAWING	
Amount Due	Date Paid		Sheets Drwg.	Figs. Drwg.
<input type="checkbox"/> TERMINAL DISCLAIMER		PREPARED FOR ISSUE	Application Examiner	
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